

United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.usplo.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/792,069	03/03/2004	Wei-Yung Hsu	AMAT/5614.D1/CMP/CMP/R	KK 4228
44257 7590 04/03/2007 PATTERSON & SHERIDAN, LLP 3040 POST OAK BOULEVARD, SUITE 1500			EXAMINER LEADER, WILLIAM T	
•			. 1742	
SHORTENED STATUTORY	Y PERIOD OF RESPONSE	MAIL DATE	DELIVERY MODE	
3 MON	VILL	04/03/2007 PAPER		PFR

Please find below and/or attached an Office communication concerning this application or proceeding.

If NO period for reply is specified above, the maximum statutory period will apply and will expire 6 MONTHS from the mailing date of this communication.

	Application No.	Applicant(s)				
	10/792,069	HSU ET AL.				
Office Action Summary	Examiner	Art Unit				
	William T. Leader	1742				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	ATE OF THIS COMMUNICATION 16(a). In no event, however, may a reply be tim rill apply and will expire SIX (6) MONTHS from the cause the application to become ABANDONED	l. ely filed the mailing date of this communication. (35 U.S.C. § 133).				
Status	•					
1) Responsive to communication(s) filed on						
·	action is non-final.					
<i>/</i>	<u> </u>					
closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims						
4) Claim(s) 1-19 is/are pending in the application.	•					
4a) Of the above claim(s) is/are withdrawn from consideration.						
5) Claim(s) is/are allowed.						
6)⊠ Claim(s) <u>1-19</u> is/are rejected.	•					
7) Claim(s) is/are objected to.						
8) Claim(s) are subject to restriction and/or	election requirement.					
Application Papers						
9) The specification is objected to by the Examiner	•					
10) ☐ The drawing(s) filed on <u>03 March 2004</u> is/are: a		by the Examiner.				
Applicant may not request that any objection to the o						
Replacement drawing sheet(s) including the correcti	-	• •				
11) The oath or declaration is objected to by the Ex	* * * * * * * * * * * * * * * * * * * *	, ,				
Priority under 35 U.S.C. § 119						
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:	priority under 35 U.S.C. § 119(a)	-(d) or (f).				
1. Certified copies of the priority documents	have been received.					
2. Certified copies of the priority documents		on No				
3. Copies of the certified copies of the prior	3. Copies of the certified copies of the priority documents have been received in this National Stage					
application from the International Bureau (PCT Rule 17.2(a)).						
* See the attached detailed Office action for a list of	of the certified copies not receive	d.				
·		·				
Attachment(s)						
1) Notice of References Cited (PTO-892)	4) Interview Summary	(PTO-413)				
2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	Paper No(s)/Mail Da	te				
B) Information Disclosure Statement(s) (PTO/SB/08) Paper No(s)/Mail Date <u>See Continuation Sheet</u> .	5) Notice of Informal Pa	atent Application				

Continuation of Attachment(s) 3). Information Disclosure Statement(s) (PTO/SB/08), Paper No(s)/Mail Date :6/2004, 8/2004, 2/2005, 12/2006.

DETAILED ACTION

Claim Rejections - 35 USC § 102

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

- 1. Claims 1, 2, 4, 5, 8-14 and 16-19 are rejected under 35 U.S.C. 102(e) as being anticipated by Uzoh et al (6,354,916).
- 2. The Uzoh patent is directed to a process for electroplating and planarization. As disclosed in example 3 which repeated example 2 using a copper electroplating solution containing an oxidizer. The substrate, which was a semiconductor wafer, was positioned in the electrolyte at a first distance from a permeable disc. The permeable disc was a polishing pad supplied by 3M. The plating solution was directed toward the wafer through openings in the anode assembly and the pad as shown in figure 2. This shows that the pad was permeable as recited in instant claims 1 and 13. A plating current was applied to cause copper to be electroplated onto the wafer. Thus, all steps recited in instant claim 13 are disclosed by Uzoh et al.
- 3. Instant claim 1 additionally recited the step of positioning the substrate a second distance from the permeable disc, the second distance being less than the first distance. In the examples of Uzoh et al, the substrate was initially positioned at a distance of around 0.1 cm (10 mm) from the pad. After an initial period of 30 seconds, the pad was pushed against the wafer. Thus, all steps recited in instant claim 1 are disclosed by Uzoh et al.

Application/Control Number: 10/792,069 Page 3

Art Unit: 1742

the pressure applied is 1 psi (example 2).

4. With respect to claims 2 and 14, as noted above, the electroplating of Uzoh et al contains copper. With respect to claims 4, 12, 16 and 19, the plating current applied by Uzoh et al was 2 amps (column 8, lines 17-8) which falls within the ranges recited by applicant. With respect to claims 5 and 17, the permeable disc of Uzoh et al is a polishing pad, as discussed above. With respect to claims 8 and 9, as noted above, Uzoh et al discloses that the pad is pushed against the wafer so that that the substrate and disk are in contact. With respect to claims 10 and 18, Uzoh et

al discloses that it is known to transfer the plated wafer to a separate CMP (chemical mechanical

polishing) apparatus (column 7, lines 1-2). With respect to claim 11, Uzoh et al discloses that

Claim Rejections - 35 USC § 103

- 5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 6. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later

Application/Control Number: 10/792,069

Art Unit: 1742

invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Page 4

- 7. Claims 3, 7 and 15 are rejected under 35 U.S.C. 103(a) as being unpatentable over Uzoh et al (6,354,916).
- 8. Claim 7 differs from the process of Uzoh et al by reciting that the initial distance is between about 1 and 5 mm. In example 1 of Uzoh the electroplating was conducted with a distance between the pad and the wafer of 0.1 cm (10 mm). However, Uzoh et al discloses that the distance between the wafer surface and the pad is adjustable (column 6, lines 51-53). The use of an intermediate distance to which the apparatus of Uzoh can be adjusted is a result-effective variable and would have been a matter of routine optimization based on other process parameters such as plating solution flow through the pad and relative pad-wafer motion. Claims 3 and 15 recite that the less that 5000 angstroms were plated at the first distance. Uzoh et al is silent as to the amount of material deposited, although example 2 discloses that the plating period at the first distance was 30 seconds. Choice of an amount at the first distance is a result-effective variable and would have been a matter of routine optimization based on the teaching of Uzoh et al. Uzoh et al discuss the effects of plating at different distances and pressures and illustrate a range of effects in figure 1. Choice from within the range illustrated in figure 1 would have been obvious because the desired results would have been obtained.
- 9. Claim 6 is rejected under 35 U.S.C. 103(a) as being unpatentable over Uzoh et al (6,354,916) in view of Taylor et al (6,210,555).

Application/Control Number: 10/792,069

Art Unit: 1742

10. The Taylor et al patent is directed to the electrodeposition of metal into small recesses

Page 5

such as those on a semiconductor wafer. Taylor et al disclose that the use of pulse current, as

described in the abstract and shown in figure 1, alleviates problems encountered when plating

into small blind holes and vias by avoiding excessive deposition on convex portions of the

substrate (column 2, lines 51-58.

11. The prior art is indicative of the level of skill of one of ordinary skill in the art. It would

have been obvious at the time the invention was made to have utilized pulse plating as disclosed

by Taylor et al in the process of Uzoh et al because problems such as excessive deposition of

edges would have been avoided.

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to William T. Leader whose telephone number is 571-272-1245.

The examiner can normally be reached on Mondays-Thursdays and alternate Fridays, 7:30-4:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Roy King, can be reached on 571-272-1244. The fax phone number for the

organization where this application or proceeding is assigned is 571-273-8300.

Application/Control Number: 10/792,069

Art Unit: 1742

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

William Leader March 29, 2007

SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 1700

Page 6